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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

03560.002558.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yuji SUDOH et al.

Application No.: 09/532,022

Filed: March 21, 2000

For: EXPOSURE APPARATUS AND A
DEVICE MANUFACTURING METHOD :
WHICH KEEP TEMPERATURE OF A :
DIAPHRAGM OF A PROJECTION :
OPTICAL SYSTEM SUBSTANTIALLY :
CONSTANT :

Examiner: H. Nguyen

Group Art Unit: 2851

August 5, 2003

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The Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

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AMENDMENT AFTER FINAL ACTION

Sir:

In response to the Office Action dated May 6, 2003, please amend the above-identified application as follows pursuant to 37 C.F.R. § 1.116:

The present Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice entitled "Amendments in a Revised Format Now Permitted," a copy of which is attached.